AMENDMENT TO THE CLAIMS

1. (Currently Amended) A semiconductor apparatus comprising:

a semiconductor chip including a power semiconductor device constructed by using a wide band gap semiconductor;

a <u>first</u> base material made of an electrically conductive material and electrically connected to a part of a lower surface of said semiconductor chip:

a heat conducting member coming in contact with a part of an upper surface of said semiconductor chip and releasing heat directly from said semiconductor chip; and

an encapsulating material for encapsulating said semiconductor chip and said heat conducting member,

wherein the semiconductor apparatus further comprises a second base material made of a metal material and connected to a part of said upper surface of said semiconductor chip,

wherein said power semiconductor device is a vertical element,

wherein a part of said <u>first</u> base material is extruded outside said encapsulating material and works as [[an]] a first external connection terminal.

wherein a part of said second base material is extruded outside said encapsulating material and works as a second external connection terminal,

wherein a first intermediate member made of an electrically conductive material and a second intermediate member made of a material having lower heat conductivity than said first intermediate member are provided between said <u>first</u> base material and said semiconductor chip, and

wherein the semiconductor chip and the <u>first</u> base material are electrically connected with each other through the first intermediate member.

- 2. (Original) The semiconductor apparatus of Claim 1,
- wherein said power semiconductor device has a region where a current passes at a current density of 50 A/cm² or more.
 - 3. (Original) The semiconductor apparatus of Claim 1 or 2, wherein said encapsulating material is made of a resin or glass, and said heat conducting member is exposed from said encapsulating material.
- 4. (Original) The semiconductor apparatus of Claim 3, further comprising a radiation fin that is in contact with said heat conducting member and is extruded outside said encapsulating material.
- (Withdrawn) The semiconductor apparatus of Claim 1 or 2, further comprising a film for covering said encapsulating material.
- (Withdrawn) The semiconductor apparatus of Claim 5, further comprising a radiation fin opposing said heat conducting member with said film sandwiched therebetween.
 - 7-11. (Cancelled)
 - 12. (Withdrawn) A semiconductor apparatus comprising:
- a semiconductor chip including a power semiconductor device constructed by using a wide band gap semiconductor;

a base material made of an electrically conductive material and connected to a part of a face of said semiconductor chip;

a heat conducting member in contact with a part of the face of said semiconductor chip;

a vessel in contact with said heat conducting member and encapsulating said

semiconductor chip, said base material and said heat conducting member; and

an external connection terminal electrically connected to said base material and extruded from said vessel.

13. (Withdrawn) The semiconductor apparatus of Claim 12,

wherein a region around said semiconductor chip, said base material and said heat conducting member within said vessel is filled with glass, a resin, an inert gas or a gas reduced in pressure.

- 14. (Withdrawn) The semiconductor apparatus of Claim 12 or 13, further comprising a radiation fin opposing said heat conducting member with a part of said vessel sandwiched therebetween.
 - 15. (Previously presented) The semiconductor apparatus of claim 1,

wherein another heat conducting member is in direct contact with the lower surface of said semiconductor chip.

- 16. (Currently amended) The semiconductor apparatus of claim 1, wherein a contact area between said semiconductor chip and said <u>first</u> base material is smaller than a half of an area of the upper or lower surface of said semiconductor chip.
- 17. (Currently amended) The semiconductor apparatus of claim 1, wherein said power-semiconductor device is a vertical element, and said-semiconductor-apparatus further emprises comprising another semiconductor chip that is stacked on said semiconductor chip and a part of which is connected to said first base material.
- 18. (Currently amended) The semiconductor apparatus of claim 1, wherein said <u>first</u> external connection terminal of said <u>first</u> base material is constructed to be mounted on a print wiring board.
 - (Previously Presented) The semiconductor apparatus of claim 1,
 wherein said wide band gap semiconductor is SiC.